

Experimental results of the simultaneous measurement of spatially varying phase and polarization

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OVERVIEW

- A novel interferometric measurement method for the simultaneous measurement of any locally varying polarization and phase distribution was developed by combining phase and polarization shifting of the reference beam.
- The investigated methods are presented by showing experimental results of light distributions generated with special polarization objects.
- The measurement objects used on this poster are based on sub-wavelength gratings with locally variant orientation made from silicon nitride.
- For more theoretical description of the method, notation and used setup \rightarrow **Poster Nr.1**

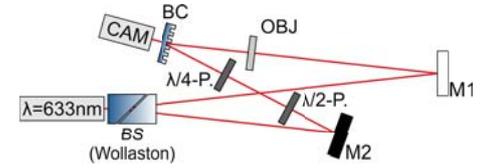
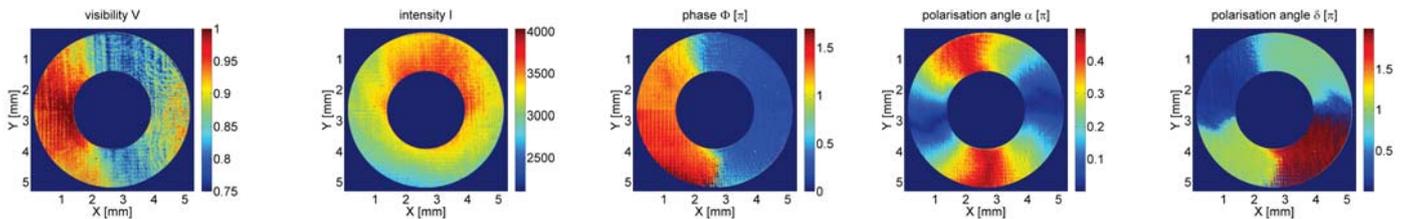


Fig. 1: Sketch of used Mach-Zehnder interferometer

MEASUREMENT RESULTS AND DISCUSSION

All five unknown values of the radially polarized light distribution generated by a polarizing element, presented on this poster below, were measured with a 4/2/2 method (Fig.2-6). This method uses four phase steps ($\phi_i \in \{0; \pi/2; \pi; 3\pi/2\}$) for each of four polarisation states ($\Psi_i \in \{0; \pi\}$; $\chi_i \in \{-\pi/4; \pi/4\}$) of the reference wave.



- The measured polarisation angles α and δ represent the expected radial polarized light. These two values can be combined to one ellipse plot (Fig.7) for more comprehensible visualization of the measured polarisation.
- The measured phase distribution is the sum of the real object phase Φ^* and an additional phase step Φ_{pol} caused by the polarisation (For the explanation of the occurrence of Φ_{pol} see Fig. 8). The pure object phase with manually removed polarisation phase step is shown in Fig. 9.

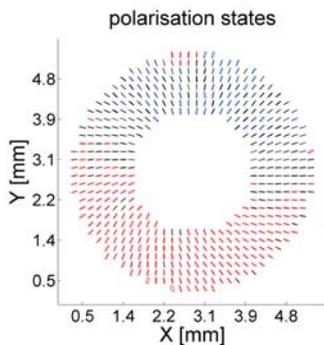


Fig. 7: Visualization of the distribution of polarisation states. (red/blue ellipses \rightarrow right/left hand polarisation)

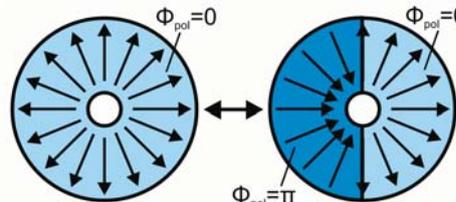


Fig. 8: Because of the limited codomain of calculated $\alpha \in [0; \frac{\pi}{2}]$ not all polarisation states can be represented with this angle. All "forbidden" states caused an additional phase step of $\Phi_{pol} = \pi$.

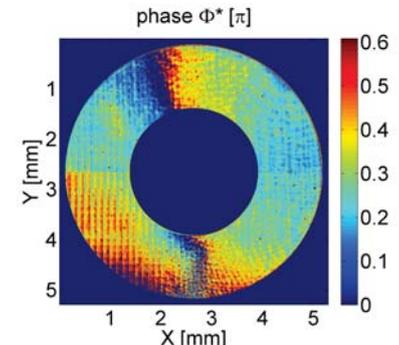


Fig. 9: The object phase with manually removed additional phase step of π caused by polarisation.

- Future research includes the improvement of the stability and precision of the setup and characterisation of the methods.
- Furthermore the decoding of the object phase and the additional phase term caused by polarisation must be solved.

POLARIZATION ELEMENTS MADE FROM Si3N4 SUB-λ GRATINGS

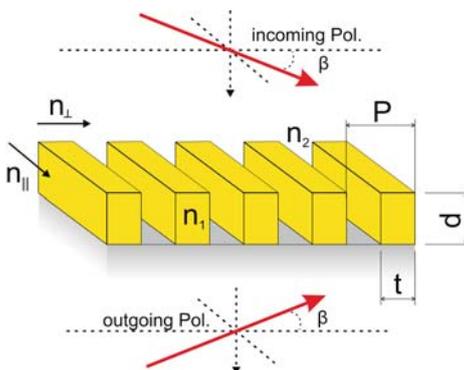


Fig. 10: Sketch of local grating geometry

- The form birefringence ($n_{\perp} \neq n_{\parallel}$) of a dielectric material (Si_3N_4) is achieved by structuring the surface in the nm-range (binary grating).
- To avoid higher diffraction orders as the zeroth order the grating period must fulfill following equation: $P < \lambda/n_{Si_3N_4} \rightarrow P < \frac{633nm}{2.01} = 314nm$
- The geometry parameters (Fig. 10) of the grating are calculated with the effective medium theory: $n_{\parallel} = \sqrt{\frac{t}{P}n_1^2 + (1 - \frac{t}{P})n_2^2}$ $n_{\perp} = \frac{n_1n_2}{\sqrt{Pn_1^2 + (1 - \frac{t}{P})n_2^2}}$
- The phase retardation that has an effect on the incoming light is a function of the grating depth: $\Delta = \frac{2\pi}{\lambda}d(n_{\parallel} - n_{\perp})$
- The final geometry parameters for structure with a local phase retardation of $\Delta = \pi$ (HWP) are: $P = 300nm$; $t = 120nm$; $d = 1050nm$;
- By choosing the correct local orientation of the gratings it is possible to fabricate e.g. a radial polarizer. The local orientation of a such space variant half wave plate is half of the azimuthal angle (Fig. 11).
- Fabrication: e-beam lithography & reactive ion etching

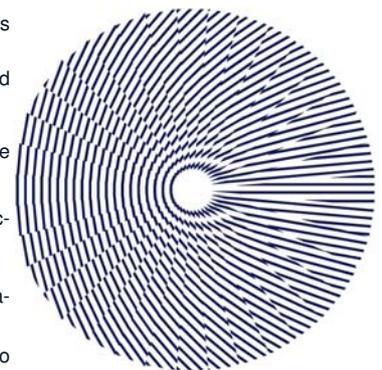


Fig. 11: Sketch of global element pattern